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WHAT IS CLAIMED IS:

1. A variable-shape mirror comprising a flexible film having a plurality of electrodes and a reflective surface whose shape varies when electrostatic forces are applied to the plurality of electrodes,

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the plurality of electrodes being divided in a circumferential direction and in a radial direction of the flexible film, and

the flexible film having a greater number of circumferential-directional divisions in a peripheral portion thereof than in a central portion thereof.

2. A variable-shape mirror comprising a flexible film having a plurality of electrodes and a reflective surface whose shape varies when an electrostatic force is applied to the plurality of electrodes,

the flexible film having, in a peripheral region, a portion having a rigidity lower than a rigidity of remaining region of the flexible film.

- 3. A variable-shape mirror according to claim 2, wherein the portion with the lower rigidity comprises a plurality of openings provided in the flexible film.
- 4. A variable-shape mirror according to claim 2, wherein the reflective surface deforms from a flat shape, and a peripheral region of the flexible film at a time of deformation has a displacement gradient varying from location to location in a direction vertical to the reflective surface when the reflective

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surface is flat, and

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a ratio of the portion with the lower rigidity to the location with a large displacement gradient is greater than a ratio of the portion with the lower rigidity to the location with a small displacement gradient.

5. A variable-shape mirror according to claim 3, wherein the reflective surface deforms from a flat shape, and a peripheral region of the flexible film at a time of deformation has a displacement gradient varying from location to location in a direction vertical to the reflective surface at a time when the reflective surface is flat, and

a ratio of the openings to the location with a large displacement gradient is greater than a ratio of the openings to the location with a small displacement gradient.

6. A variable-shape mirror comprising a flexible film having a plurality of electrodes and a reflective surface whose shape varies when an electrostatic force is applied to the plurality of electrodes,

the flexible film including a portion with a low rigidity in a circumferential direction thereof, and a ratio of the portion with the low rigidity varies in the circumferential direction of the flexible film.

7. A variable-shape mirror comprising a flexible film having a plurality of electrodes and a reflective

surface whose shape varies when an electrostatic force is applied to the plurality of electrodes,

the flexible film including openings in a circumferential direction thereof, and a ratio of the openings varies in the circumferential direction of the flexible film.

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- 8. A variable-shape mirror according to claim 7, wherein a diameter of each of the opening is shorter than a wavelength of light reflected by the reflective surface.
 - 9. A variable-shape mirror comprising:
 - a plurality of fixed lower electrodes; and
- a flexible film having a reflective surface and a plurality of upper electrodes,
- the lower electrode has, in a region thereof, a plurality of openings arranged at different intervals, and

the flexible film has, in a peripheral portion thereof, a portion having a rigidity lower than a rigidity of other regions of the flexible film.

- 10. A variable-shape mirror according to claim 9, wherein the portion with the lower rigidity comprises a plurality of openings provided in the flexible film.
- 11. A method of manufacturing a variable-shape mirror, comprising:

forming first and second protection films on first and second major surfaces of a semiconductor substrate;

forming a flexible film on the first protection film;

forming a plurality of openings in the flexible film;

forming an electrode film on the flexible film;
forming an opening in the second major surface and
the second protection film, and forming a frame by a
residual portion of the semiconductor substrate.